

Supplementary Information

Improved response time of flexible microelectromechanical sensors employing eco-friendly nanomaterials

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Measurement setup illustration:

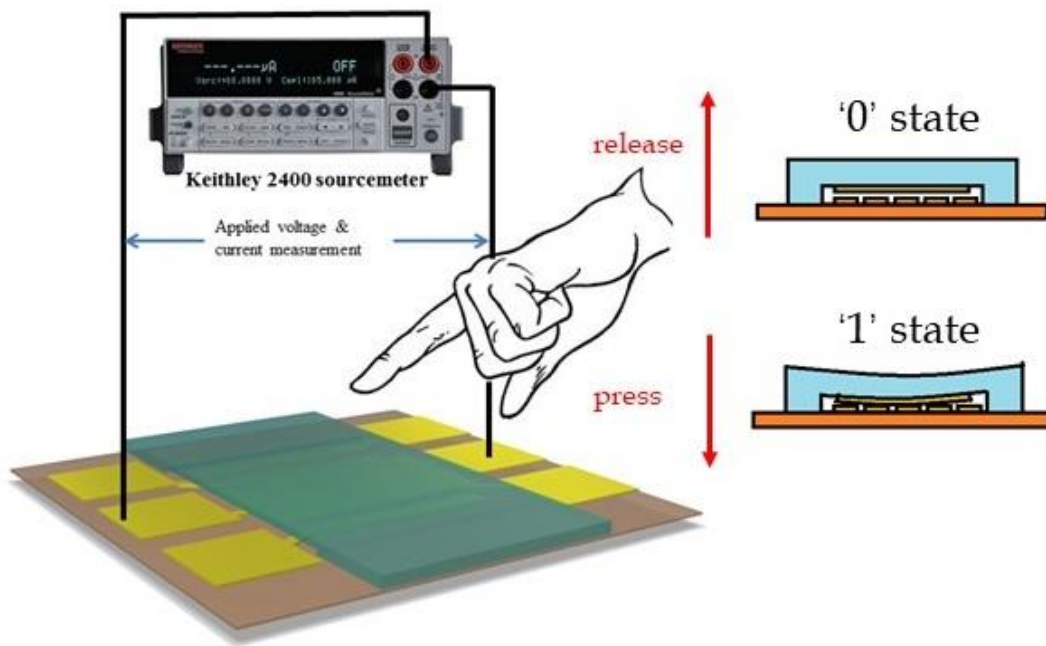


Figure S1 Measurement setup illustration of digital MEM sensors.

Finite element method (FEM) simulation of MEM sensors with different CNC/PDMS ratios and heights:

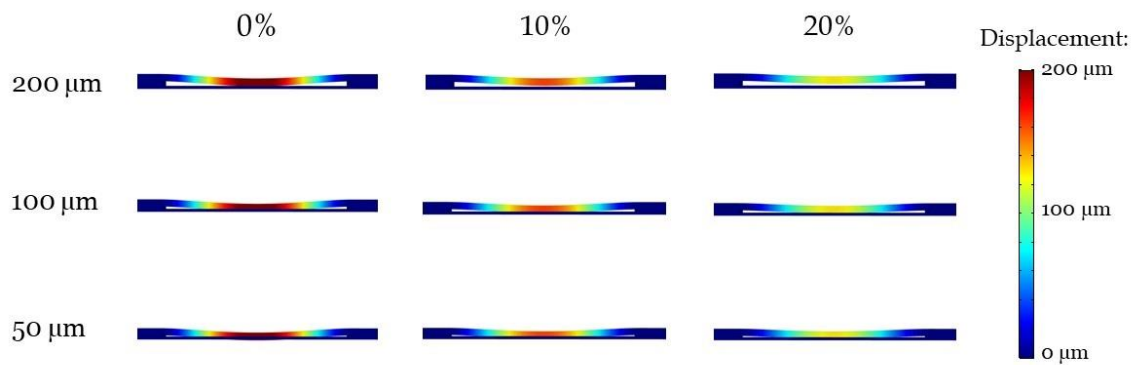


Figure S2 FEM simulation of MEM sensors with different CNC/PDMS ratios and pier heights. From left to right, the 3 columns represent 3 different CNC/PDMS ratios. From top to bottom, the

3 rows represent sensors with 3 different pier heights. The colors on simulated pier heights represent displacement when 50 Pa pressure is applied on top of the bridge structure.